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	APPLICANT MATSUI	
	FILING DATE Nov. 13, 2000	GROUP

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REFERENCE DESIGNATION

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS
HS	5,750,434	May 12, 1998	Urushidani et al.	—	—
HS	5,800,577	Sept. 1, 1998	Kido	—	—

FOREIGN PATENT DOCUMENTS

TRANSLATION

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	NAME	CLASS	SUB CLASS	YES	NO
HS	7-80770 (cited in spec. p. 4)	3/95	JAPAN	—	—	—	—	—
HS	56-23746 (cited in spec. p. 5)	6/81	JAPAN	—	—	—	—	—
HS	7-288243	10/95	JAPAN	—	—	—	X	ABSTRACT only
HS	8-22503	3/96	JAPAN	—	—	—	X	ABSTRACT
HS	664540	12/94	EPO	—	—	—	—	—

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, etc.)

HS	Kikuchi et al., "Mechanochemical Polishing of Silicon Carbide Single Crystal with Chromium(III) Oxide Abrasive", J. Am. Ceram. Soc., 75 [1], pp. 189-94 (1992) (Note: This article is discussed at page 4 of the specification).
EXAMINER	DATE CONSIDERED
<i>[Signature]</i>	10/31/01